

## Lecture 7

# MOS Capacitor

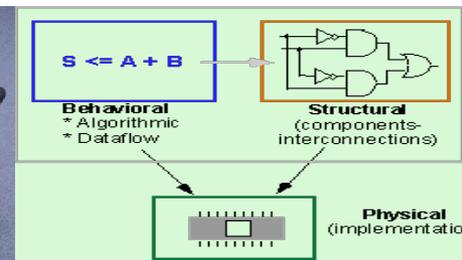
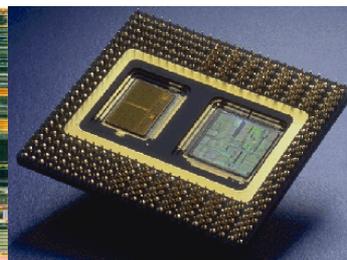
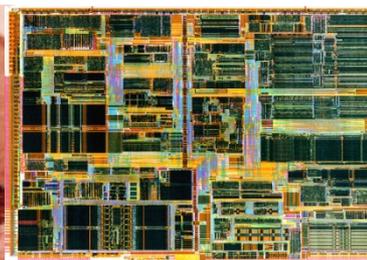
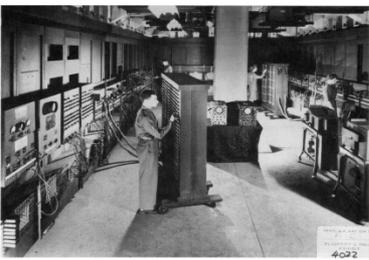
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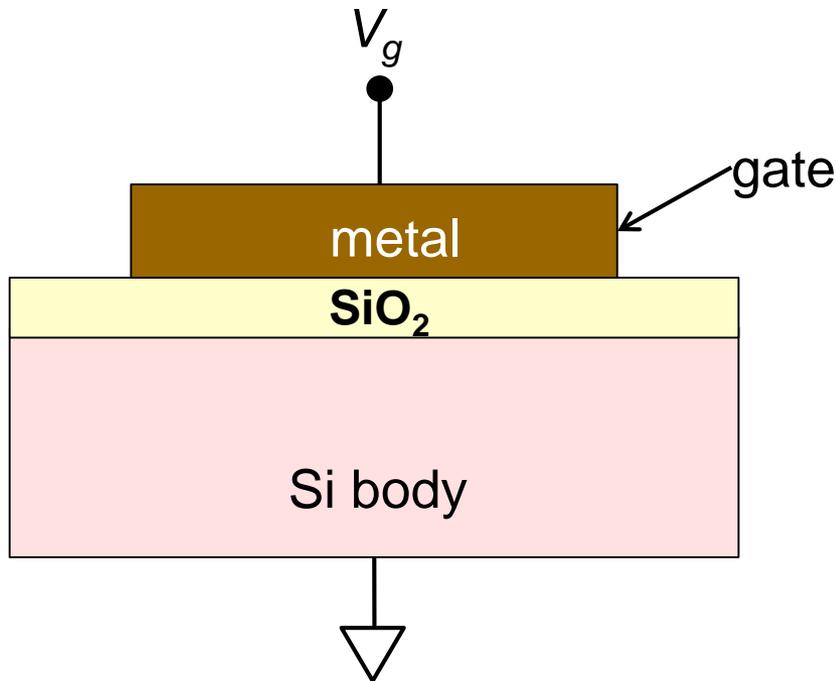
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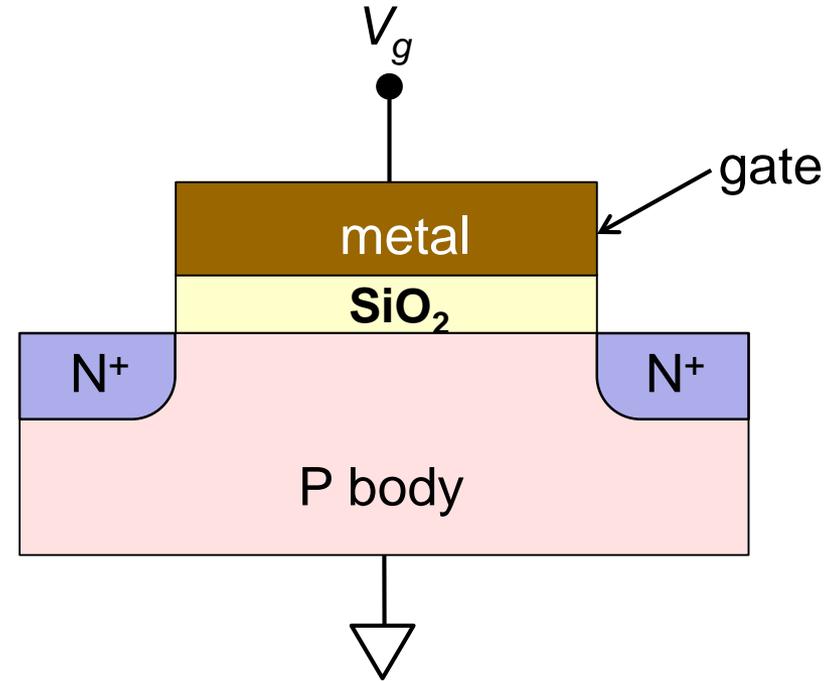
Adapted from Modern Semiconductor Devices for Integrated Circuits, Chenming Hu, 2010



# MOS Metal-Oxide-Semiconductor



**MOS capacitor**

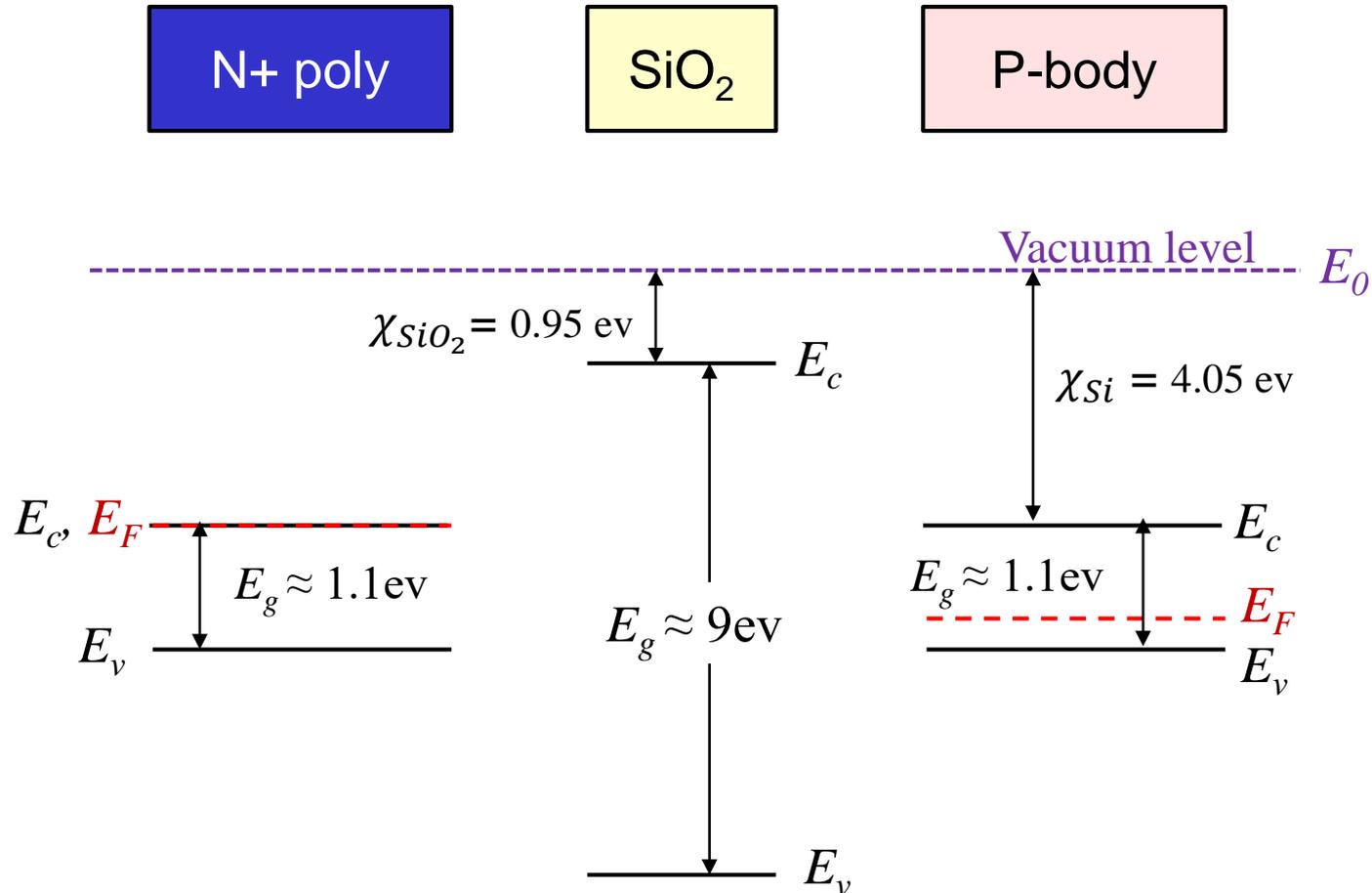


**MOS transistor**

- Gate oxide film can be as thin as 1.5nm
- After 1970, gate usually made from heavily doped polysilicon
- Trend today is to return to metal gates

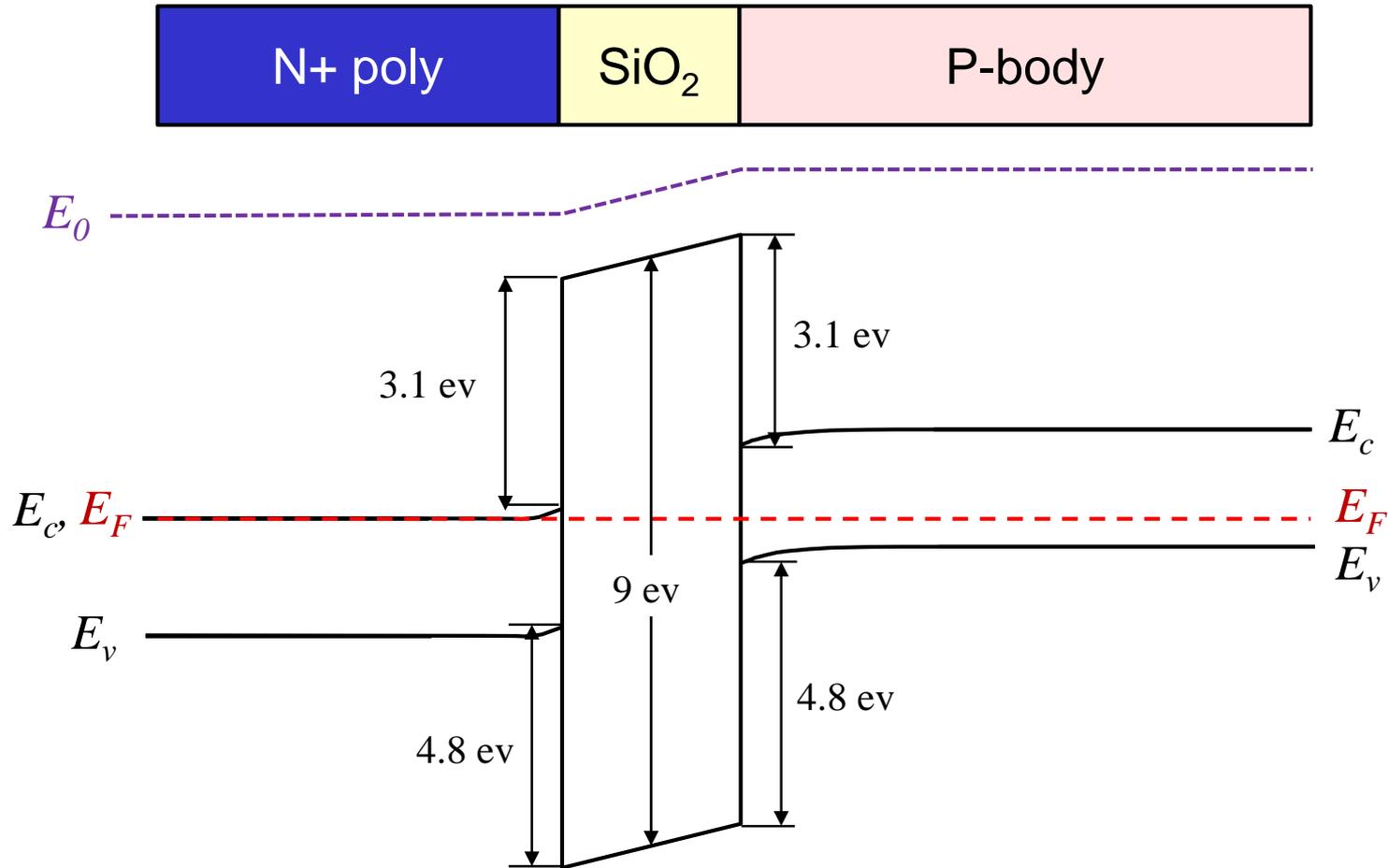
# MOS Capacitor - Energy Band Diagram

- Three different materials:



# MOS Capacitor – Thermal Equilibrium ( $V_g=0$ )

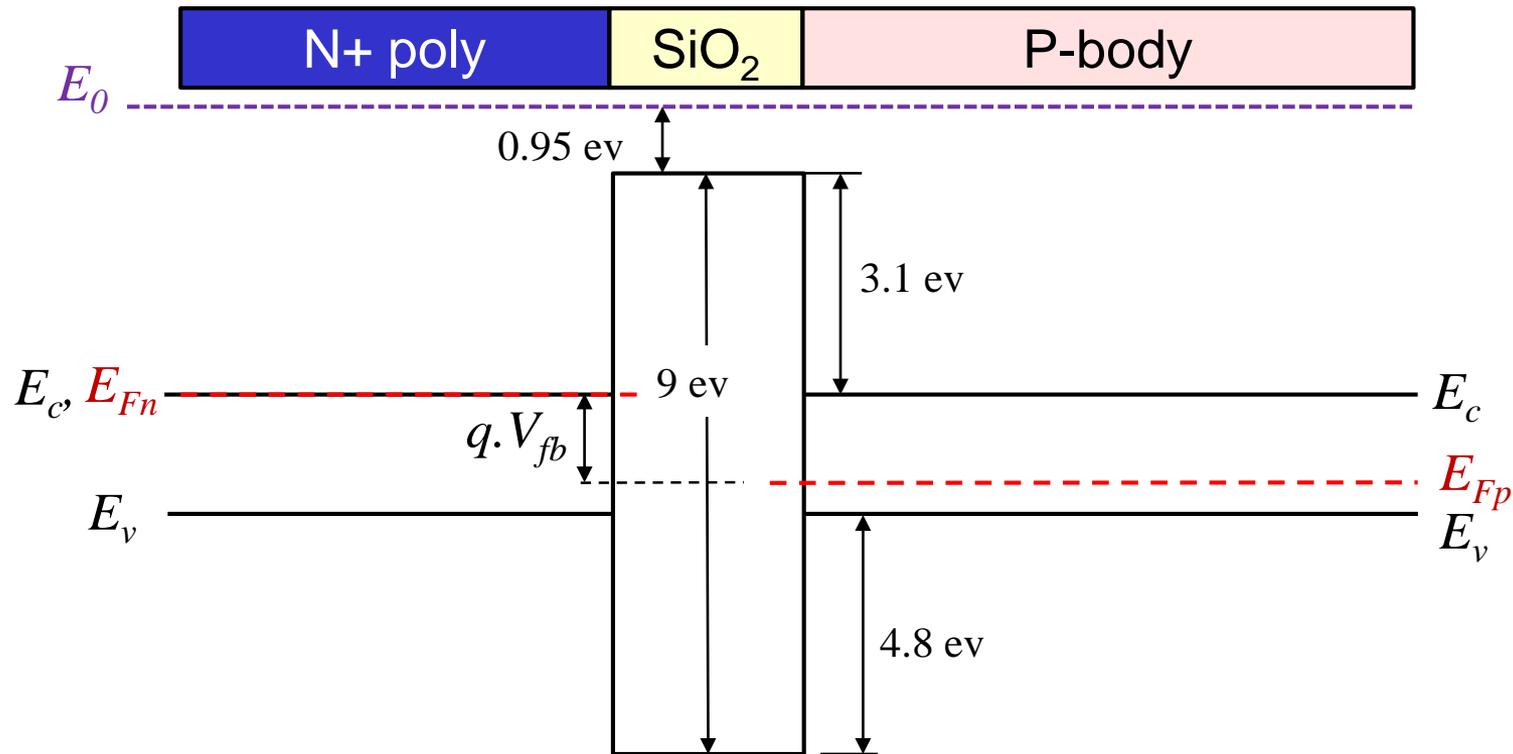
- What happens when we bring these materials together?



- Potential difference between N<sup>+</sup> gate and P body at zero bias
  - analogous to built-in voltage of PN junction

# Flat Band Condition

- Necessary to apply small negative voltage  $V_{fb}$  on gate to make energy bands flat at oxide surface

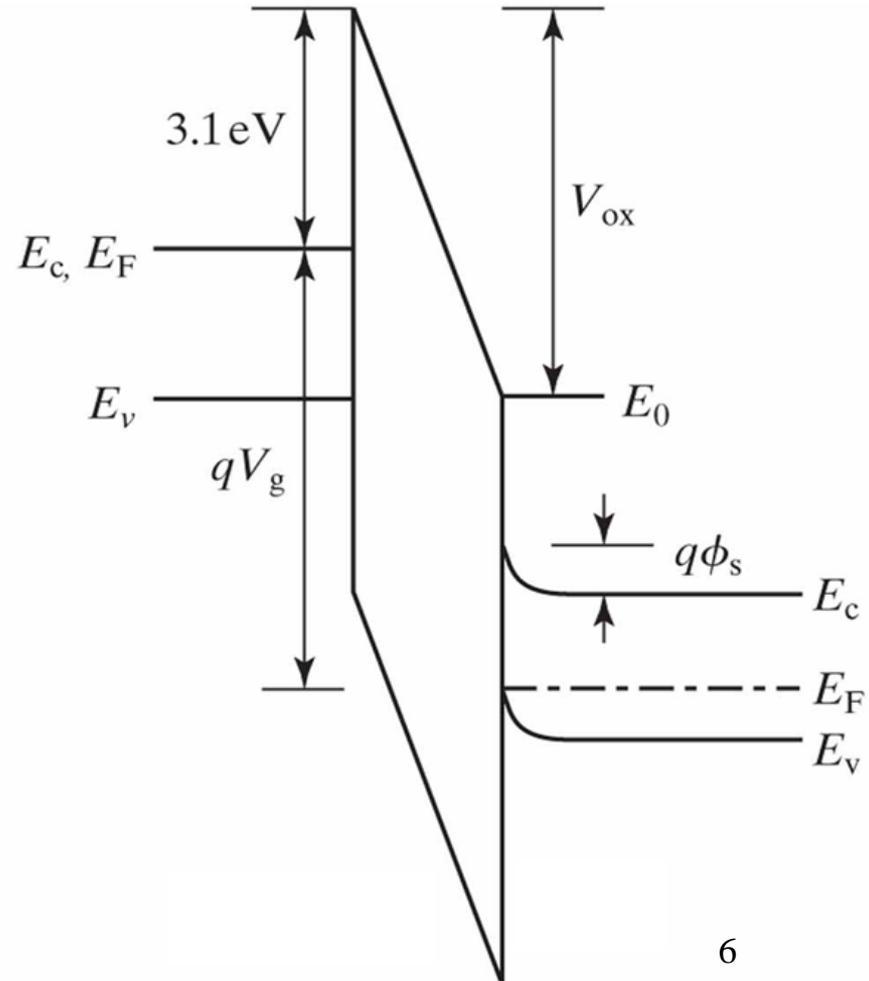
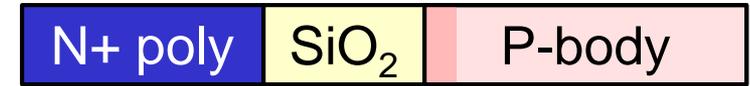


- Flat-band voltage  $V_{fb}$  is equal to difference in Quasi-Fermi levels between two terminals under flat-band conditions
- For heavily doped N+ gate:

$$V_{fb} \approx (E_{Fp} - E_c) / q = (E_{Fp} - E_v - E_g) / q$$

# Surface Accumulation

- What happens if we take  $V_g < V_{fb}$  ?
- Band diagram on gate side pushed upward
- $E_c$  on body side bends up towards oxide surface
- Surface potential  $\phi_s$  is a measure of amount of band bending
  - note that  $\phi_s$  is negative if band bend upwards
- $V_{ox}$  is potential across the oxide
  - also negative in accumulation
- $V_g$  is the potential of gate relative to the body



$$V_g = V_{fb} + \phi_s + V_{ox}$$

- In flat-band,  $\phi_s = V_{ox} = 0$

# Charge Accumulation

- Negative voltage on gate attracts majority holes to surface
- Because  $E_v$  is closer to  $E_F$  at surface (compared to bulk), surface concentration is higher than  $p_0$

$$p_s = N_a \cdot e^{-q\phi_s/kT}$$

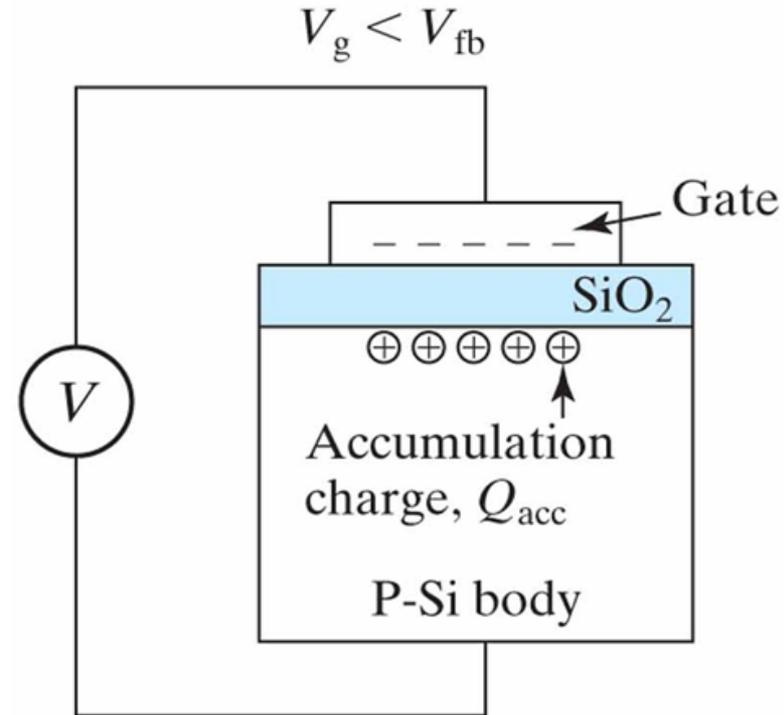
$$\phi_s = -\frac{kT}{q} \cdot \ln\left(\frac{p_s}{N_a}\right)$$

If  $\phi_s = -100 \text{ mV}$ ,  $p_s \approx 50 \times N_a$

If  $\phi_s = -200 \text{ mV}$ ,  $p_s \approx 2200 \times N_a$

- In accumulation,  $\phi_s$  is small and can be ignored in a first order model which gives:

$$V_{ox} = V_g - V_{fb}$$



# Accumulation Capacitance

- Gauss's Law: 
$$\vec{E}_{ox} = -\frac{Q_{acc}}{\epsilon_{ox}}$$

$$V_{ox} = \vec{E}_{ox} \cdot T_{ox} = -\frac{Q_{acc} \cdot T_{ox}}{\epsilon_{ox}} = -\frac{Q_{acc}}{C_{ox}}$$

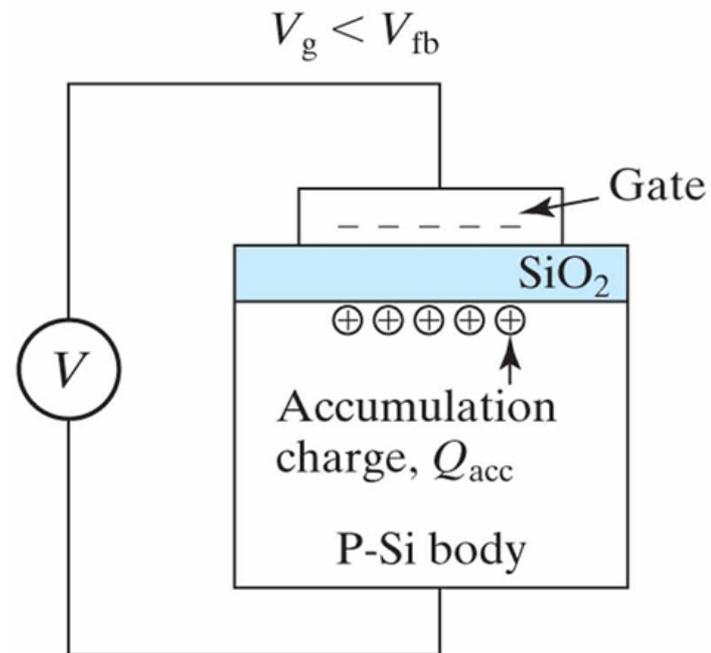
$$Q_{acc} = -C_{ox}(V_g - V_{fb})$$

- MOS capacitor in accumulation behaves like regular capacitor with ( $Q = -C \cdot V$ ) but with a shift in  $V$  by  $V_{fb}$

- negative sign because voltage is measured at gate while charge is measured on body

- More generally: 
$$V_{ox} = -\frac{Q_{bod}}{C_{ox}}$$

where  $Q_{bod}$  is total charge in body (including  $Q_{acc}$ )



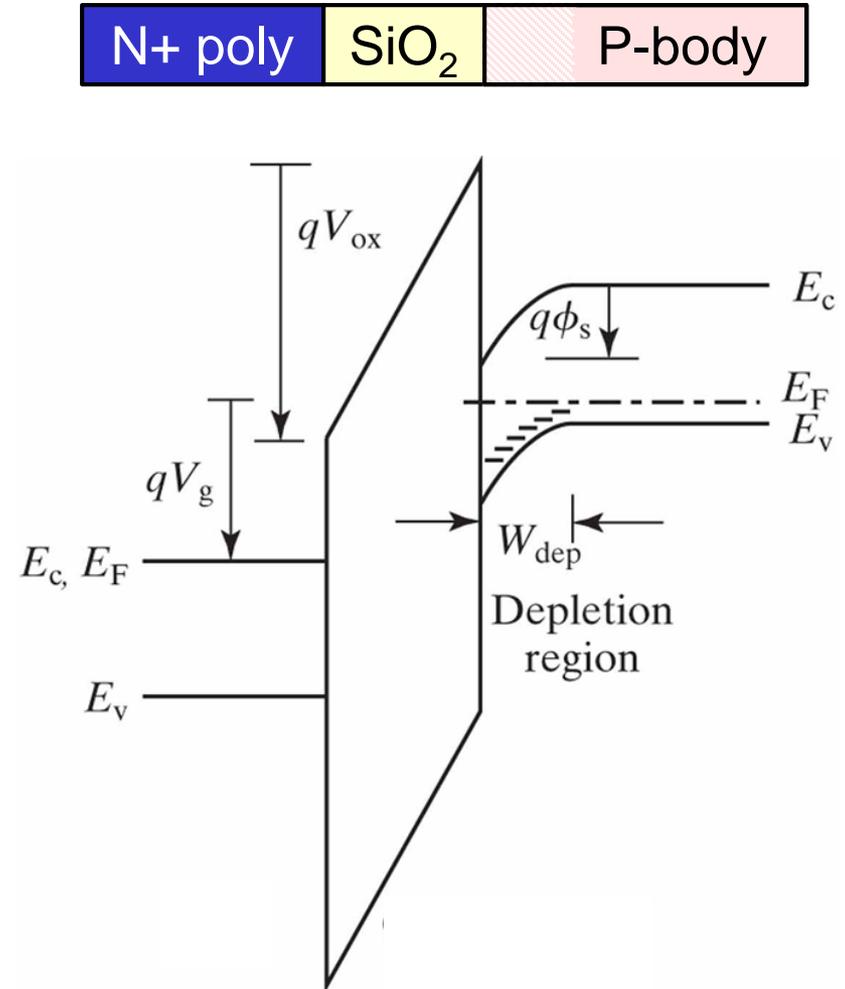
$Q_{acc}$  is accumulated charge per unit area (C/cm<sup>2</sup>)

$T_{ox}$  is oxide thickness (cm)

$C_{ox}$  is oxide capacitance per unit area (F/cm<sup>2</sup>)

# Surface Depletion

- What happens if we take  $V_g > V_{fb}$  ?
- Band diagram on gate side pulled downward
- $E_c$  on body side bends down towards oxide surface
- More positive voltage on gate repels majority holes from surface
- Because  $E_F$  is now far from  $E_c$  and  $E_v$  at surface, electron and hole densities are both small.
- There is now a depletion region at the surface with residual negative charge due to uncompensated acceptor ions



# Depletion Width

$$V_{ox} = -\frac{Q_{bod}}{C_{ox}} = -\frac{Q_{dep}}{C_{ox}}$$
$$= \frac{q \cdot N_a \cdot W_{dep}}{C_{ox}}$$

- Using Poisson's eqn. as we did with reverse biased PN junction:

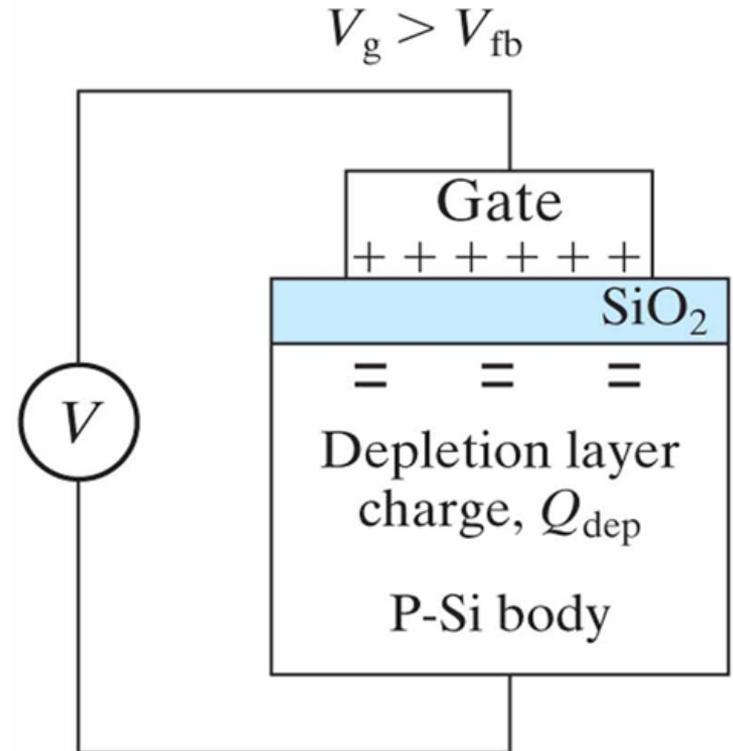
$$W_{dep} = \sqrt{(2\varepsilon_s \cdot \phi_s) / q \cdot N_a}$$

- which gives:

$$V_{ox} = \frac{\sqrt{2q \cdot N_a \cdot \varepsilon_s \cdot \phi_s}}{C_{ox}}$$

and

$$\phi_s = \frac{q \cdot N_a \cdot W_{dep}^2}{2\varepsilon_s}$$



# Charge Depletion

- As  $V_g$  increases, hole concentration at surface decreases as electron concentration at surface increases

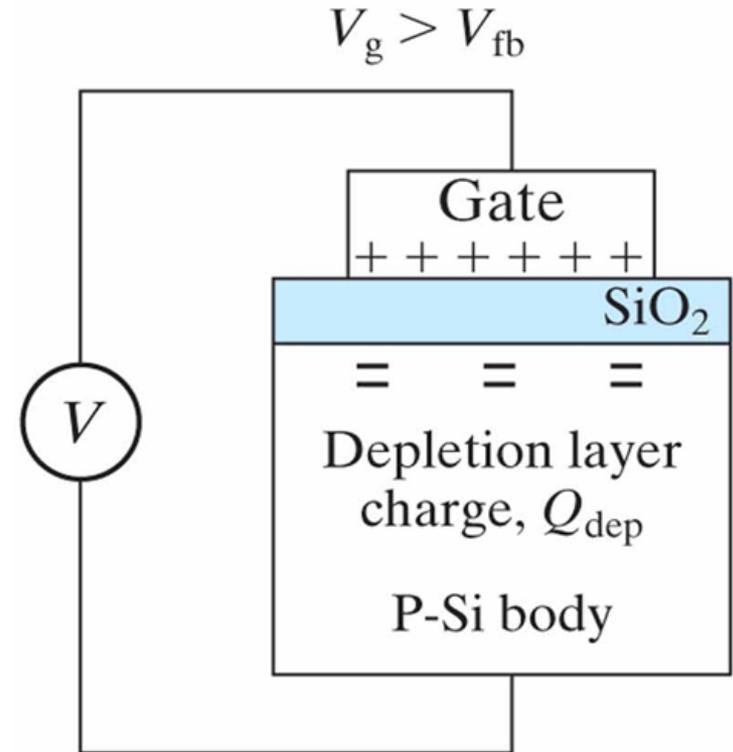
$$p_s = N_a \cdot e^{-q\phi_s/kT}$$

$$n_s = \frac{n_i^2}{N_a} \cdot e^{+q\phi_s/kT}$$

- In depletion,  $\phi_s$  is no longer negligible
  - can solve following quadratics to yield  $\phi_s$  or  $W_{dep}$  as a function of  $V_g$

$$V_g = V_{fb} + \phi_s + V_{ox} = V_{fb} + \phi_s + \frac{\sqrt{2q \cdot N_a \cdot \epsilon_s \cdot \phi_s}}{C_{ox}}$$

$$V_g = V_{fb} + \frac{q \cdot N_a \cdot W_{dep}^2}{2\epsilon_s} + \frac{q \cdot N_a \cdot W_{dep}}{C_{ox}}$$



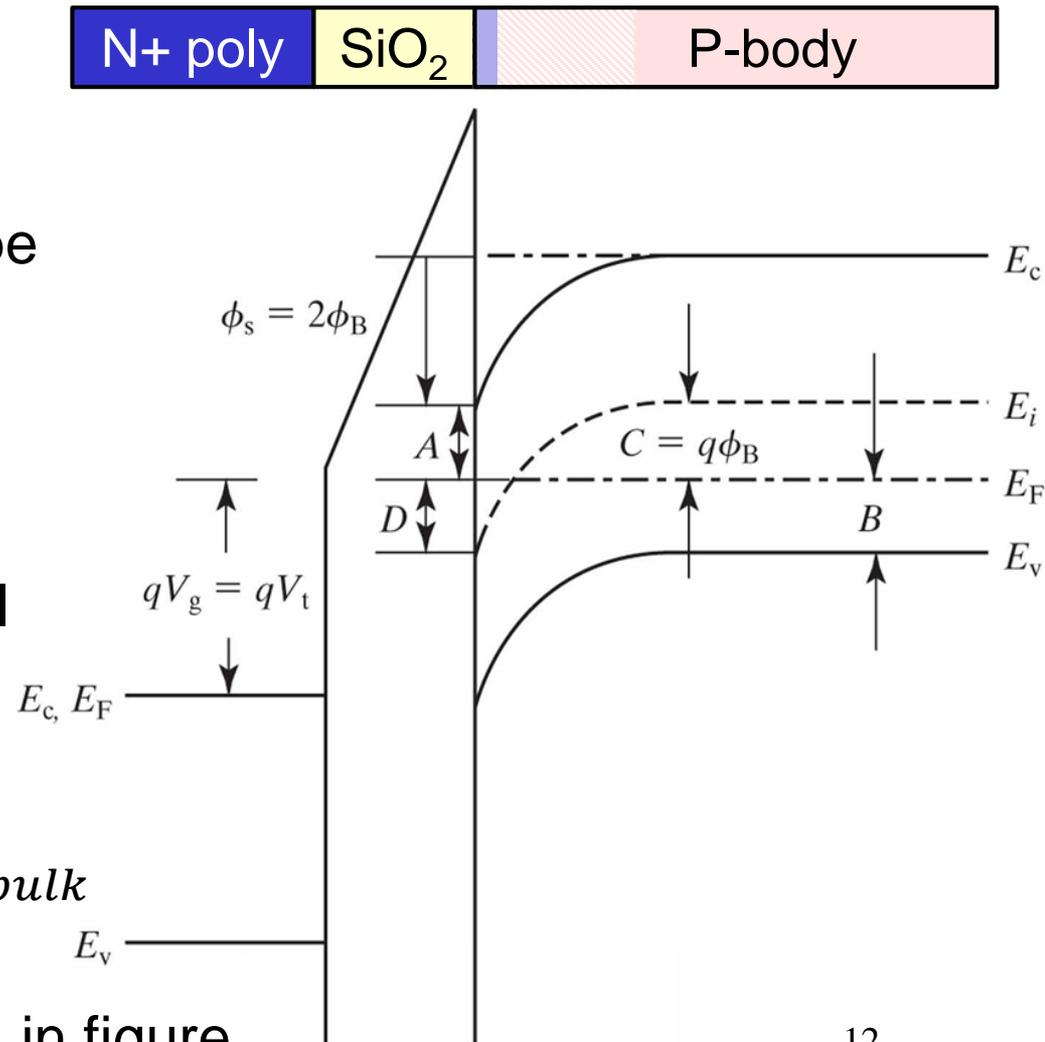
# Surface Inversion

- What happens if we make  $V_g$  increasingly more positive?
- $p_s$  continues to decrease
- $n_s$  continues to increase
- At some point, surface changes from P-type to N-type – this is called **inversion**
- **Threshold of inversion** is defined as that condition in which surface electron concentration becomes equal to bulk hole concentration

$$n_s = N_a$$

$$(E_c - E_F)_{surface} = (E_F - E_v)_{bulk}$$

i.e.,  $A = B$  which implies  $C = D$  in figure





# Threshold Voltage

$$V_g = V_{fb} + \phi_s + V_{ox}$$

- Substituting:

$$V_{ox} = \frac{\sqrt{2q \cdot N_a \cdot \epsilon_s \cdot \phi_s}}{C_{ox}} \quad \text{and} \quad \phi_s = \phi_{st} = 2\phi_B$$

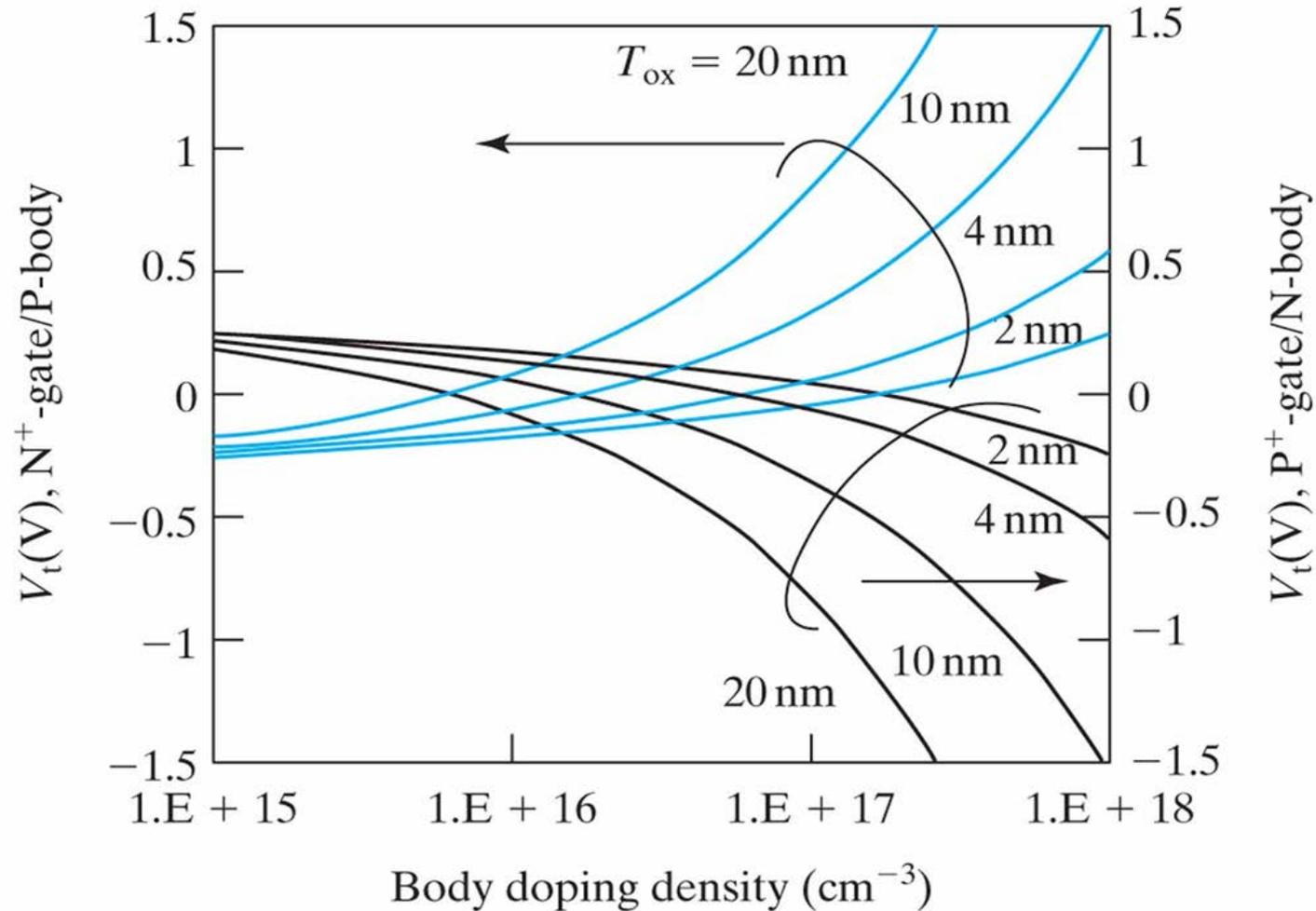
$$V_t = (V_g)_{\text{at threshold}} = V_{fb} + 2\phi_B + \frac{2 \cdot \sqrt{q \cdot N_a \cdot \epsilon_s \cdot \phi_B}}{C_{ox}}$$

- For N-type body:

$$V_t = V_{fb} - 2\phi_B - \frac{2 \cdot \sqrt{q \cdot N_d \cdot \epsilon_s \cdot \phi_B}}{C_{ox}} \quad \text{and} \quad \phi_{st} = -2\phi_B$$

$$\phi_B = \frac{kT}{q} \ln \frac{N_d}{n_i} \quad (\text{note that } \phi_B \text{ is always positive})$$

# Threshold Voltage vs. Body Doping



$$V_t = V_{fb} \pm 2\phi_B \pm \frac{2 \cdot \sqrt{q \cdot N_{body} \cdot \epsilon_s \cdot \phi_B}}{C_{ox}}$$

+ for P-body  
- for N-body

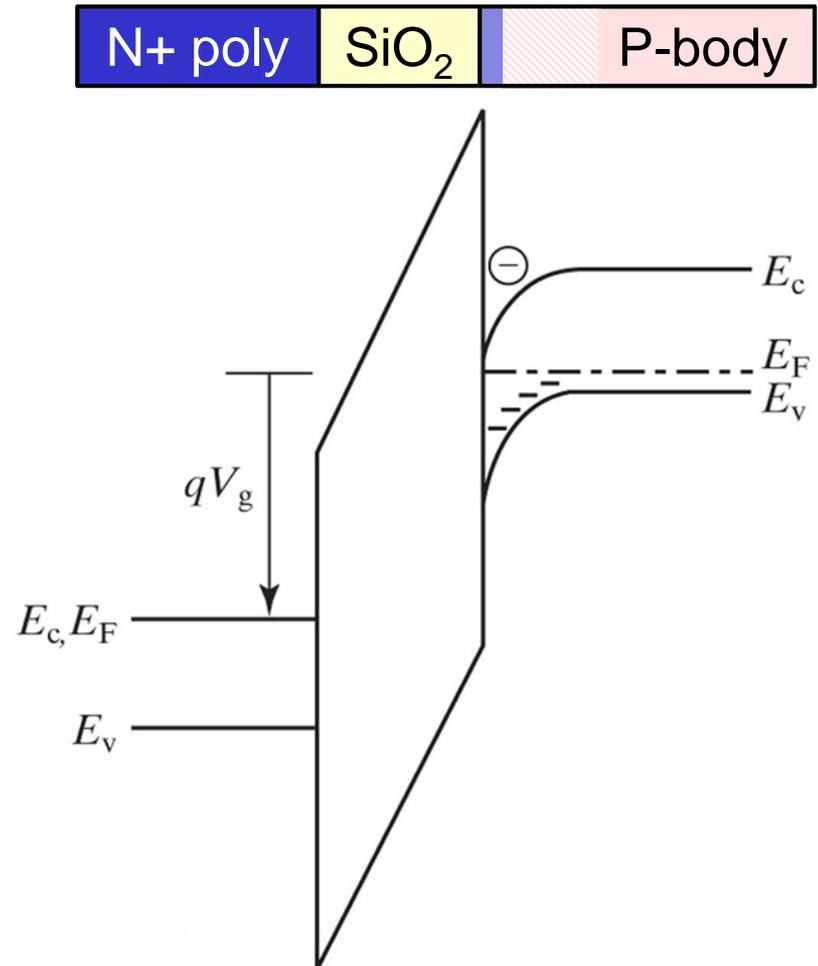
# Strong Inversion

- If we increase  $V_g$  beyond  $V_t$  . . .
- There is now an inversion layer filled with inversion electrons
- Surface electron concentration increases dramatically with small increase in  $\phi_s$

$$n_s = N_a \cdot e^{q(\phi_s - 2\phi_B)/kT}$$

- Again, to a first order,  $\phi_s$  does not increase significantly beyond  $2\phi_B$
- Which implies depletion width has reached its maximum value

$$W_{dmax} = 2 \cdot \sqrt{\frac{\epsilon_s \cdot \phi_B}{q \cdot N_a}}$$



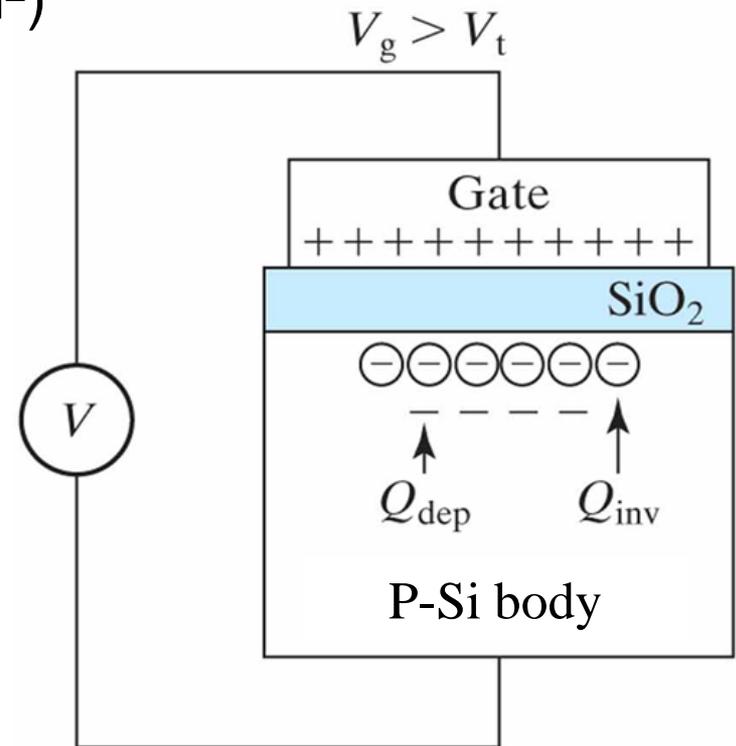
# Strong Inversion Charge

- $Q_{inv}$  is inversion charge density (C/cm<sup>2</sup>)

$$\begin{aligned} V_g &= V_{fb} + \phi_s + V_{ox} \\ &= V_{fb} + 2\phi_B - \frac{Q_{dep\_max}}{C_{ox}} - \frac{Q_{inv}}{C_{ox}} \\ &= V_t - \frac{Q_{inv}}{C_{ox}} \end{aligned}$$

- i.e.,  $Q_{inv} = -C_{ox}(V_g - V_t)$

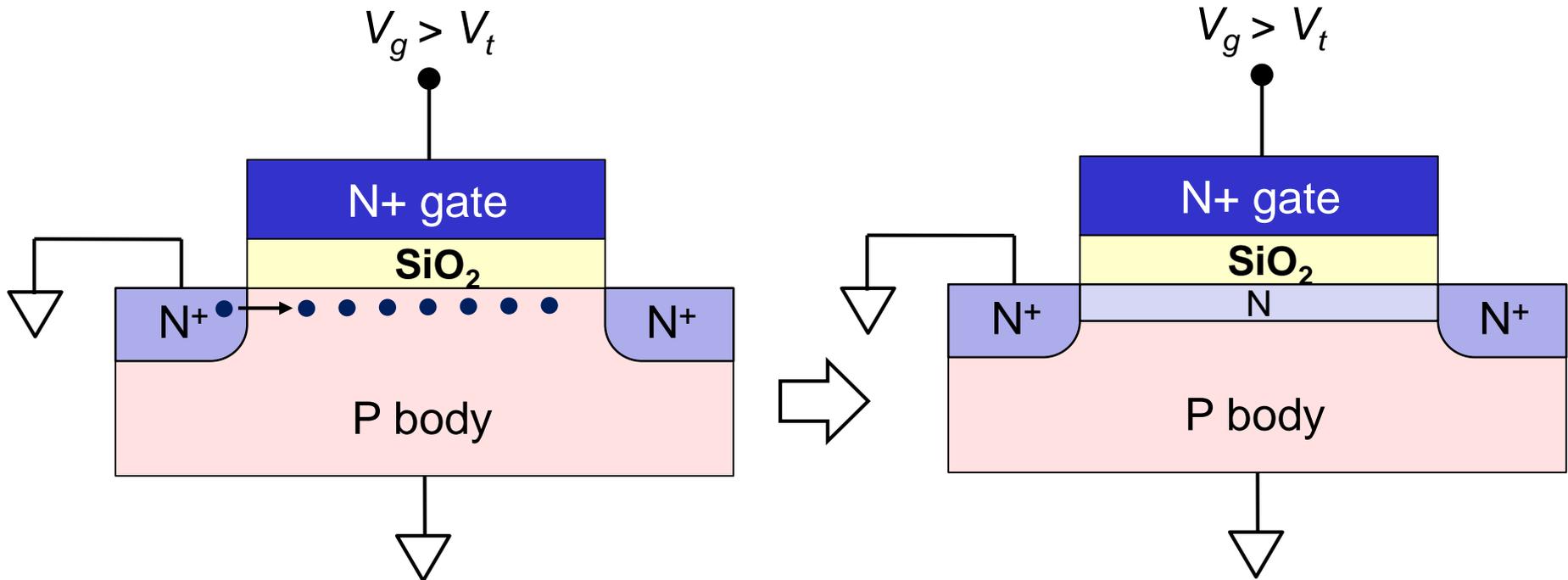
- MOS capacitor in strong inversion behaves as a capacitor with a voltage offset of  $V_t$



*Where do all these electrons come from?*

# MOS Transistor in Strong Inversion

- In MOS capacitor, inversion electrons generated thermally
  - can take many seconds in modern high quality silicon processes
- In MOS transistor, electrons rapidly supplied by N<sup>+</sup> source

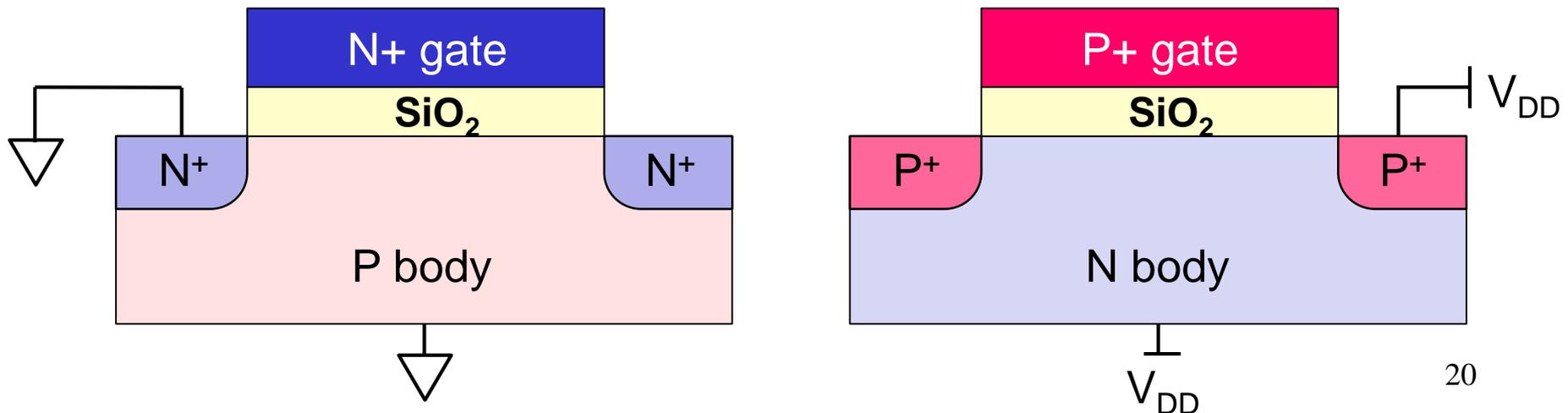


# Example: MOS Capacitor

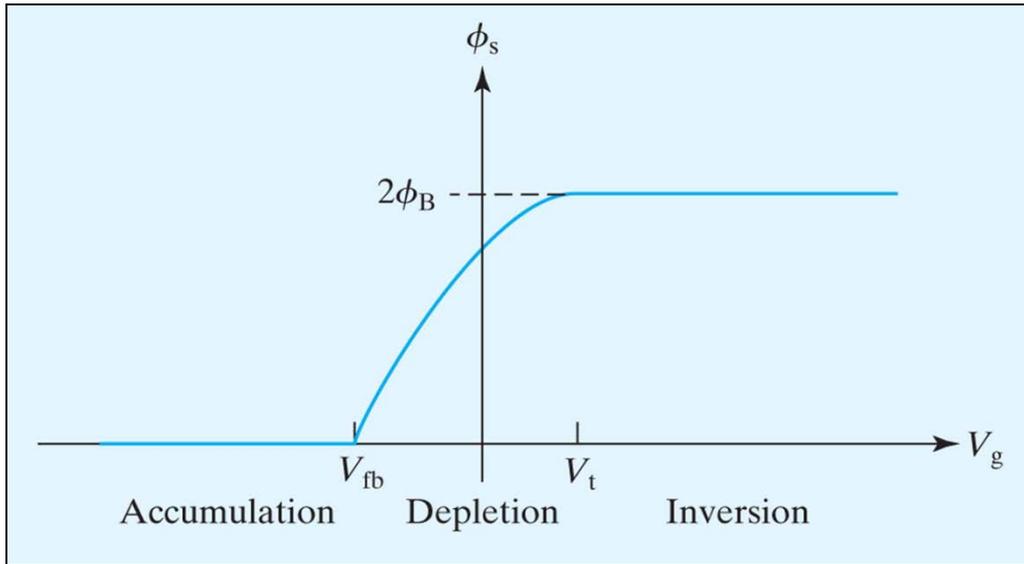
- Consider an ideal MOS capacitor fabricated on a P-type silicon substrate with a doping of  $5 \times 10^{16} \text{ cm}^{-3}$  with an oxide thickness of  $10 \text{ nm}$  and an  $\text{N}^+$  poly gate. Determine:
  - a) Bulk potential  $\phi_B$
  - b) Flat-band voltage  $V_{fb}$  of this capacitor
  - c) Oxide capacitance per unit area
  - d) Threshold voltage  $V_t$
  - e) Maximum depletion width  $W_{dmax}$
  - f) What would be the threshold if the poly gate were changed to heavy  $\text{P}^+$  doping?

# Gate Doping and Threshold Voltage

- P-body transistor normally operates in an IC with signal voltages that range from zero (ground) to some positive supply ( $V_{DD}$ )
- $V_t$  is normally set to a small positive voltage (e.g., 0.4V) so that the transistor does not have an inversion layer at  $V_g = 0V$ 
  - A transistor that does not conduct at  $V_{gs} = 0$  is known as an **enhancement** mode transistor
  - P+ gate is not normally used with P-body device as it would raise threshold voltage too high ( $> 1V$ )
- N-body device is paired with P+ gate to give small negative  $V_t$



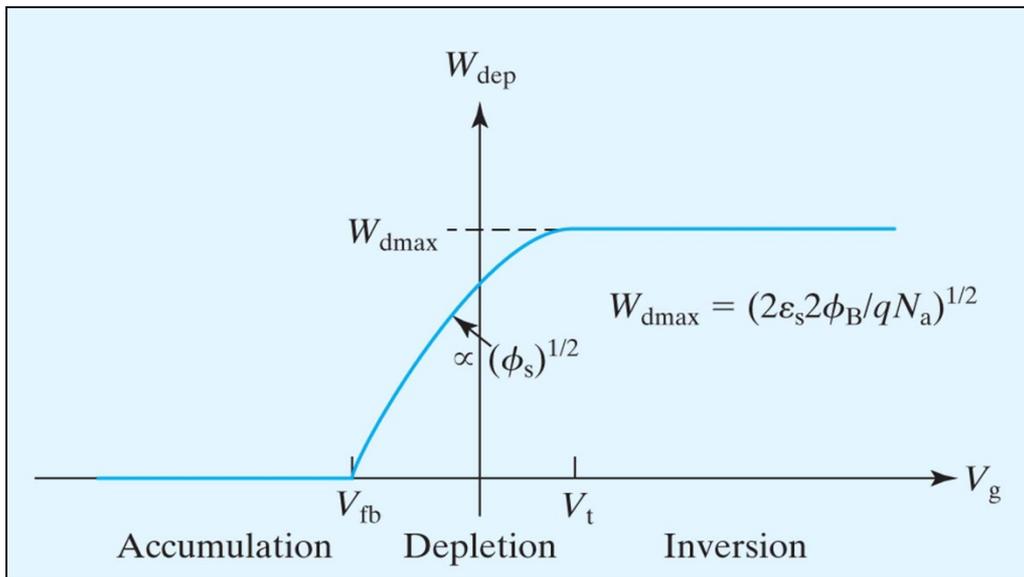
# MOS Substrate Charge - Review



$\phi_s$  is zero at  $V_{fb}$  and near zero in accumulation region

As  $V_g$  increases above  $V_{fb}$ ,  $\phi_s$  increases until surface is inverted and  $\phi_s = 2\phi_B$

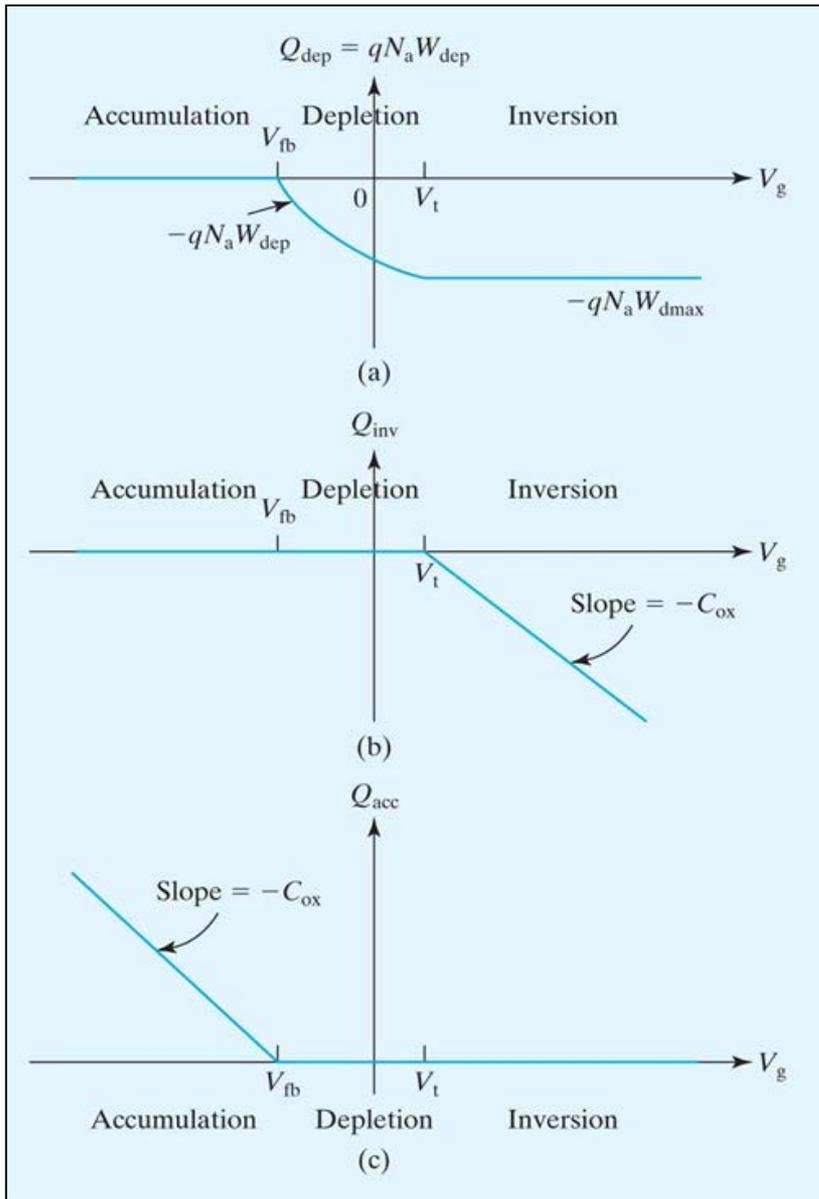
$\phi_s \approx 2\phi_B$  in inversion region



$W_{dep}$  increases as the square root of the surface potential

At  $V_g = V_t$ ,  $W_{dep}$  reaches its maximum value

# Substrate Charge Components



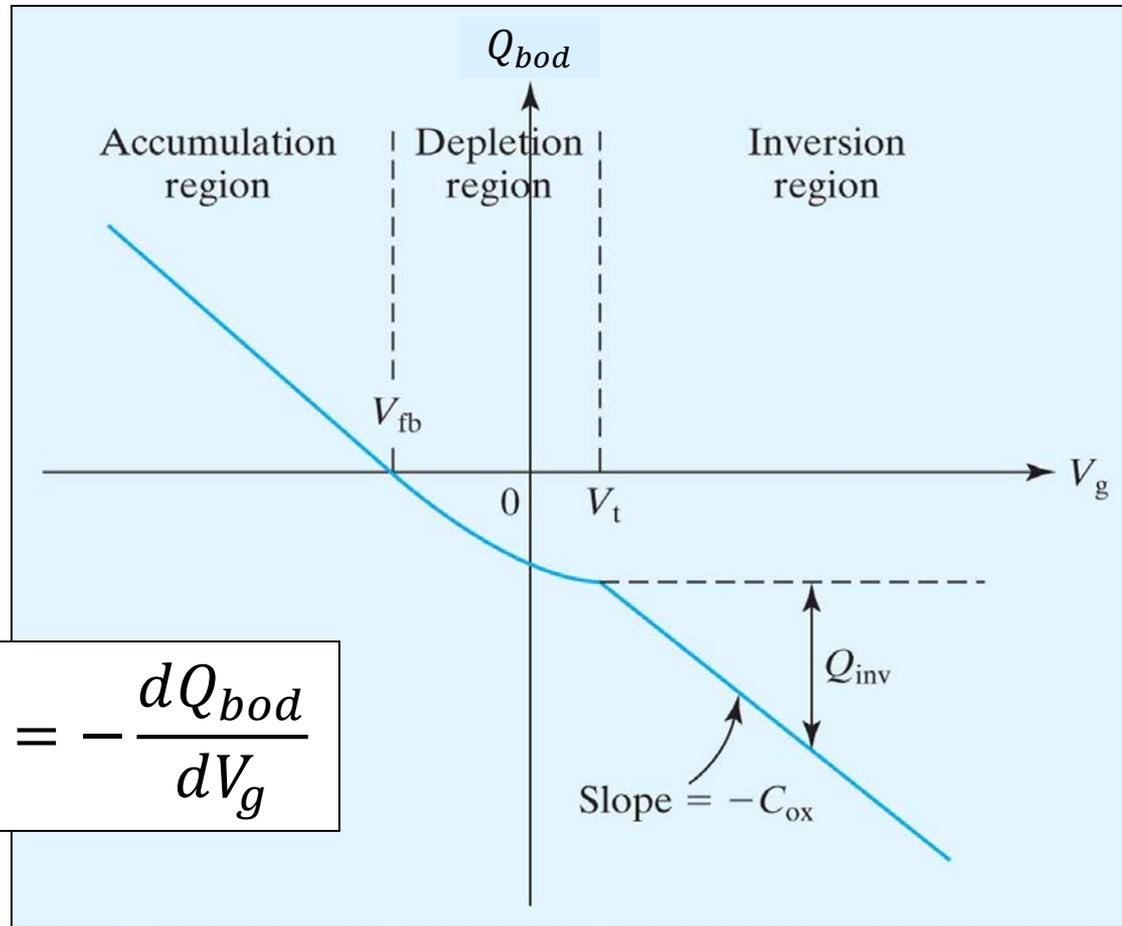
$$Q_{dep} = -q \cdot N_a \cdot W_{dep}$$

$$Q_{inv} = -C_{ox}(V_g - V_t)$$

$$Q_{acc} = -C_{ox}(V_g - V_{fb})$$

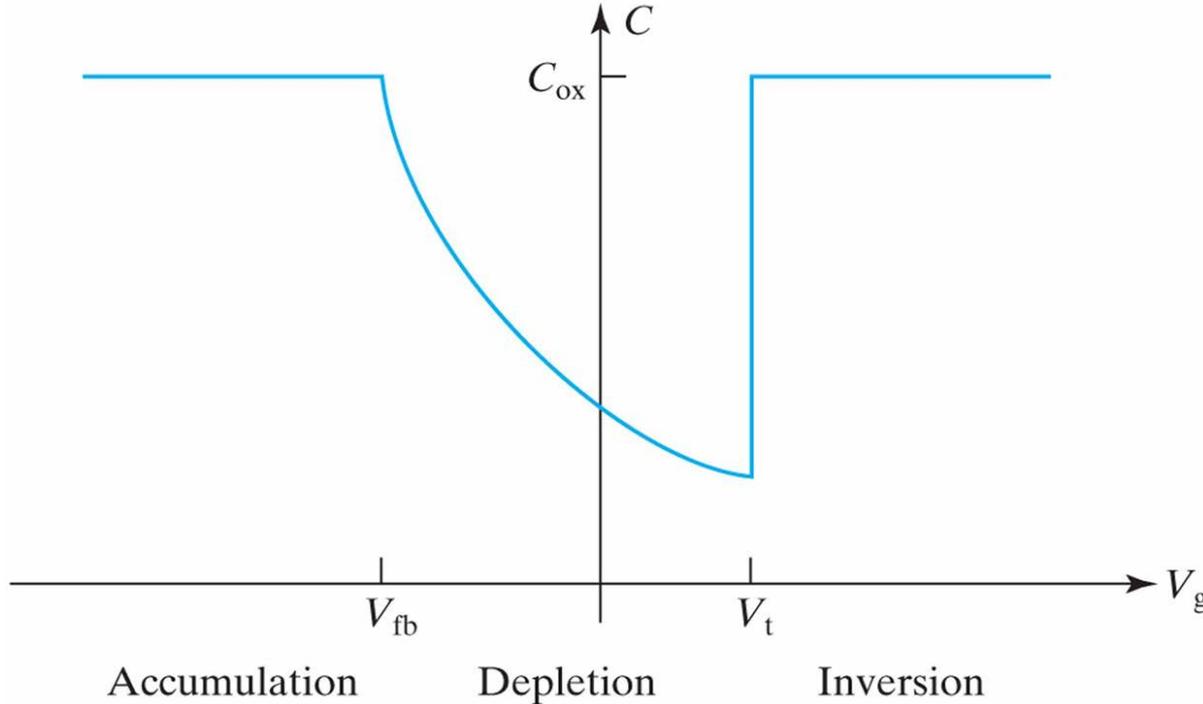
# Total Substrate Charge

$$Q_{bod} = Q_{acc} + Q_{dep} + Q_{inv}$$

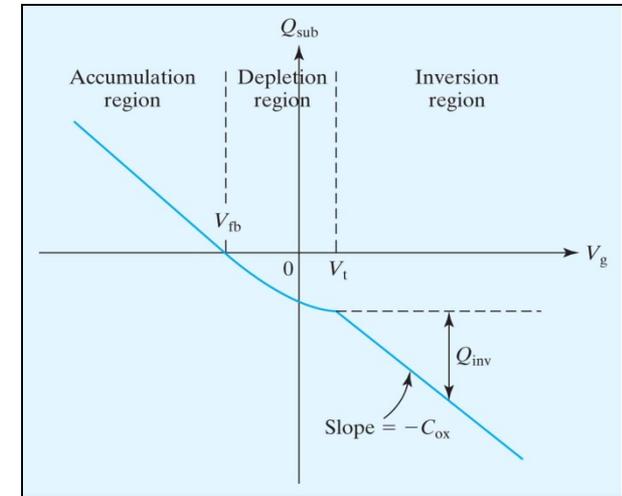


$$C \equiv \frac{dQ_g}{dV_g} = - \frac{dQ_{bod}}{dV_g}$$

# MOS C-V Characteristics



$$C \equiv \frac{dQ_g}{dV_g} = - \frac{dQ_{sub}}{dV_g}$$



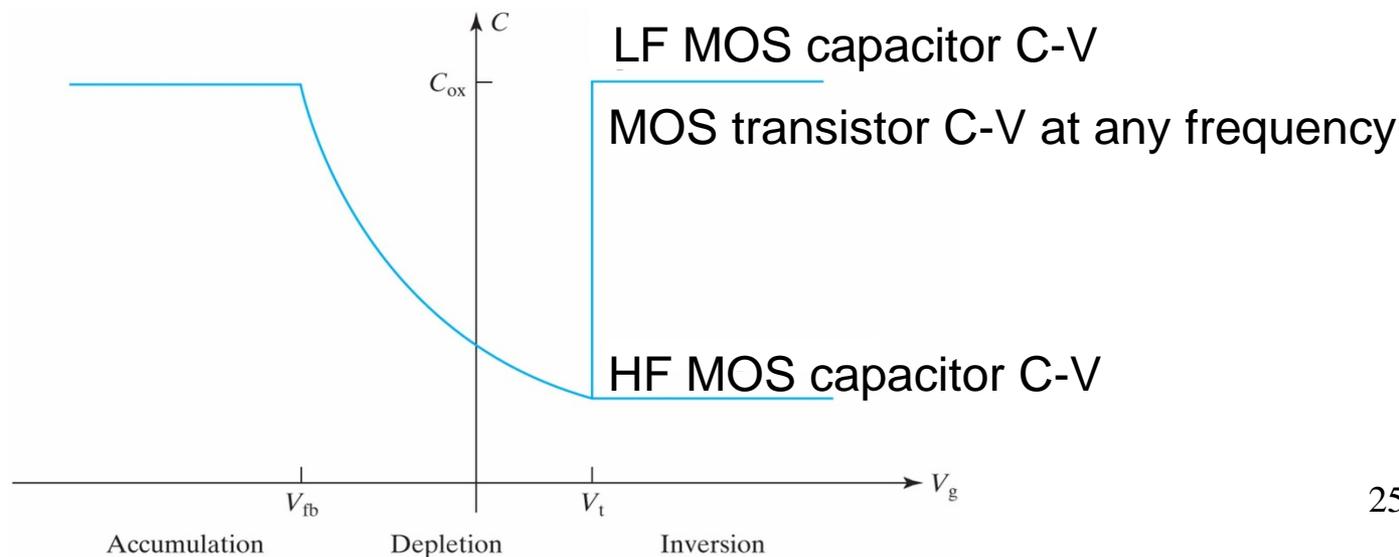
- In depletion regime,  $C$  consists of two capacitors  $C_{ox}$  and  $C_{dep}$  in series:

$$\frac{1}{C} = \frac{1}{C_{ox}} + \frac{1}{C_{dep}} \quad \text{and} \quad C_{dep} = \frac{\epsilon_s}{W_{dep}}$$

- Substituting for  $W_{dep}$ :
- $$\frac{1}{C} = \sqrt{\frac{1}{C_{ox}^2} + \frac{2(V_g - V_{fb})}{q \cdot N_a \cdot \epsilon_s}}$$

# MOS Capacitor C-V vs MOS Transistor C-V

- At high frequencies, MOS capacitor cannot (thermally) generate electrons fast enough to produce an inversion layer consistent with applied voltage  $V_g$ 
  - so for  $V_g > V_t$ , C remains at maximum depletion value
  - In modern processes, high frequencies (in this context) may mean more than a few hertz!
- MOS Transistor has a good supply of electrons from nearby  $N^+$  source region



## Example: Capacitance Values

- A  $10_{\mu m} \times 10_{\mu m}$  MOS capacitor is built with a  $N^+$  poly gate on a P-type substrate with  $N_a = 10^{17} \text{ cm}^{-3}$  and a gate oxide thickness of  $50 \text{ nm}$ .
- What are the high and low frequency capacitances of the MOS capacitor when biased in strong inversion?

# Second Order Effects

- So far, have ignored possibility of electric charge in oxide
  - fixed charge due to silicon ions at Si-SiO<sub>2</sub> interface
  - mobile charge due to impurities in oxide
  - sodium is a serious potential contaminant

- Oxide charge shifts flat-band voltage

$$V_{fb} \approx (E_F - E_c)/q - Q_{ox}/C_{ox}$$

- This, in turn, shifts threshold voltage
  - very serious in low voltage processes
- So far, have assumed accumulation and inversion layers to be zero width
  - Quantum solution of Poisson's eqn. at SiO<sub>2</sub> interface yields finite layer thickness ~ 5-15 Å
  - Effectively locates charge below interface by  $T_{inv}$
  - Reduces C in accumulation and inversion domains
  - Reduces transistor performance with thin gate oxides (<10nm)<sup>27</sup>

# Polysilicon Gate Depletion

- So far, we have ignored any band bending in N<sup>+</sup> poly gate
  - poly is heavily doped but there will be small surface potential  $\phi_{poly}$  when body is biased into inversion
- Creates a thin depletion layer in poly at SiO<sub>2</sub> interface

- Gauss's Law gives:

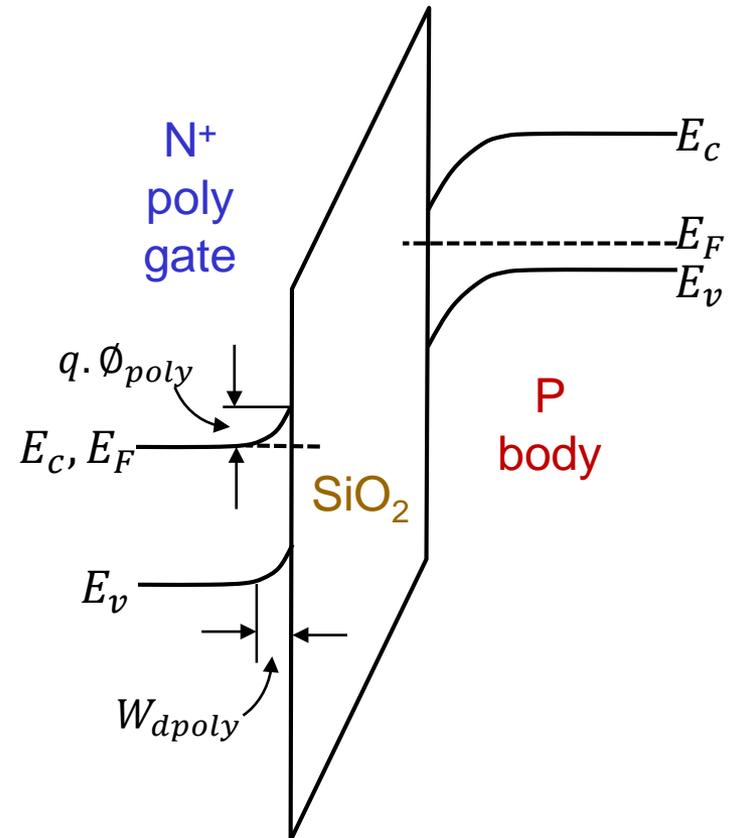
$$W_{dpoly} = \epsilon_{ox} \cdot \vec{E}_{ox} / q \cdot N_{poly}$$

- $W_{dpoly}$  may be 1-2 nm
- Solving Poisson's Equation:

$$\phi_{poly} = \frac{-q \cdot N_{poly} \cdot W_{dpoly}^2}{2 \cdot \epsilon_s}$$

- Summing potentials across interface:

$$V_g = V_{fb} + \phi_{st} + V_{ox} - \phi_{poly}$$



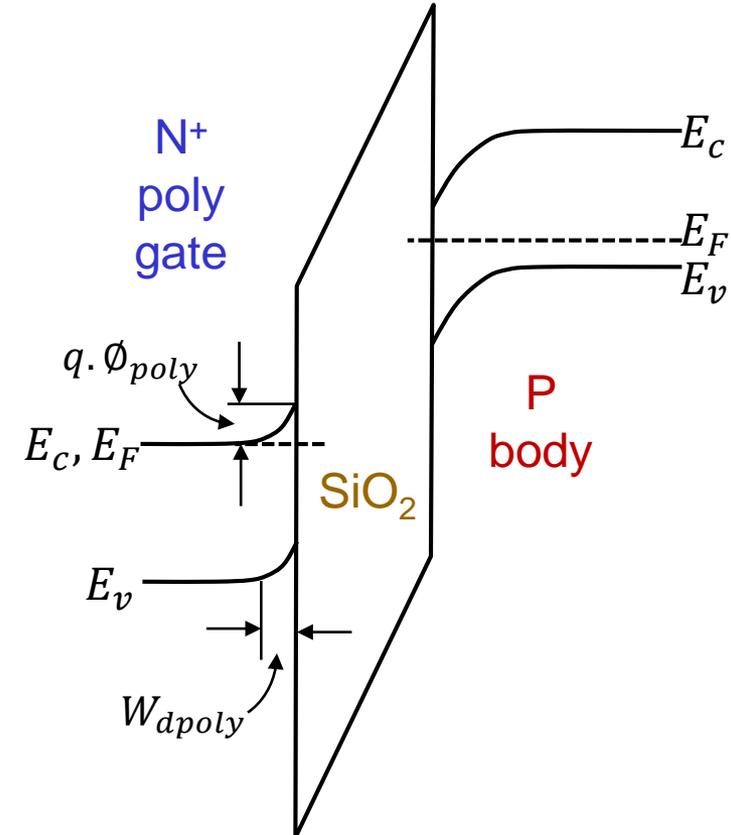
# Effects of Polysilicon Gate Depletion

- Gate Depletion decreases gate capacitance:

$$C = \left( \frac{1}{C_{ox}} + \frac{1}{C_{poly}} \right)^{-1} = \left( \frac{T_{ox}}{\epsilon_{ox}} + \frac{W_{dpoly}}{\epsilon_s} \right)^{-1}$$
$$= \frac{\epsilon_{ox}}{T_{ox} + (W_{dpoly}/3)}$$

- Also, effectively reduces gate voltage:

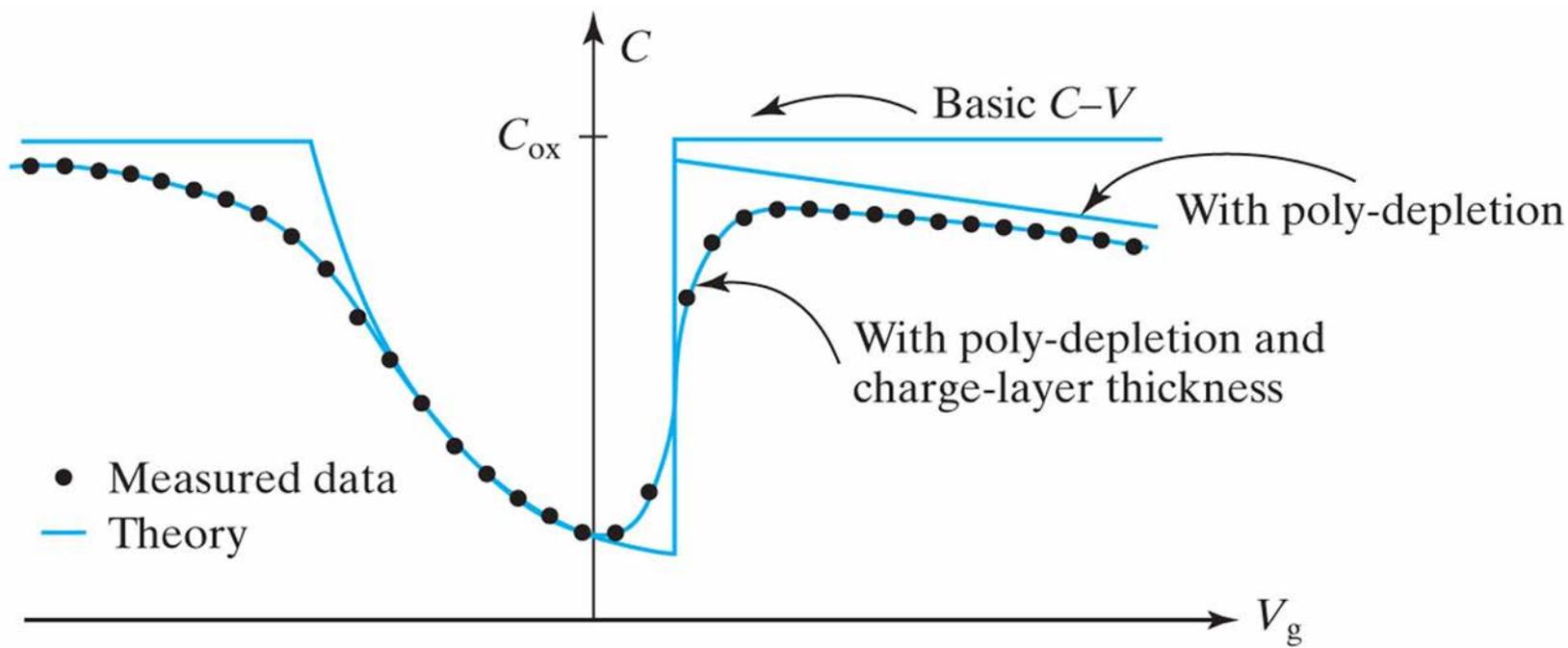
$$Q_{inv} = -C_{ox}(V_g - |\phi_{poly}| - V_t)$$



# Effective Oxide Capacitance

- Effective oxide thickness:  $T_{oxe} = T_{ox} + W_{dpoly}/3 + T_{inv}/3$
- Effective oxide capacitance:  $C_{oxe} = \epsilon_{ox}/T_{oxe}$

$$Q_{inv} = -C_{oxe}(V_g - V_t)$$



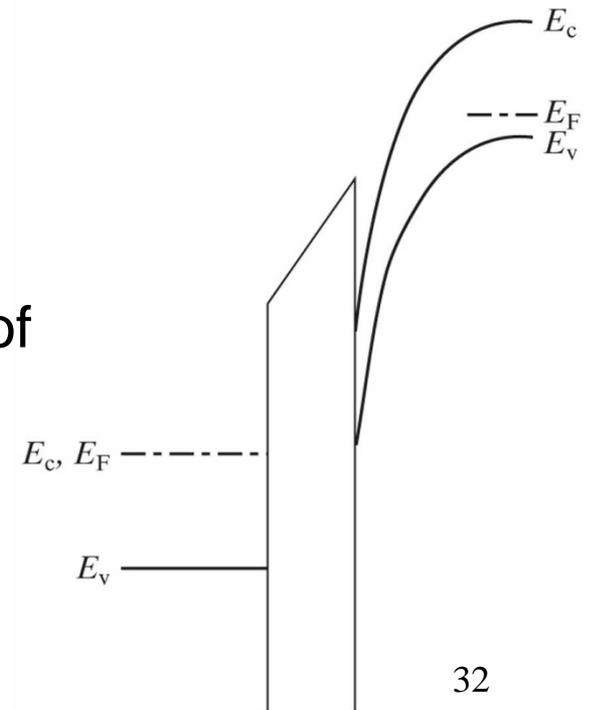
- Poly depletion can be eliminated with metal gate

# Example: Poly Gate Depletion

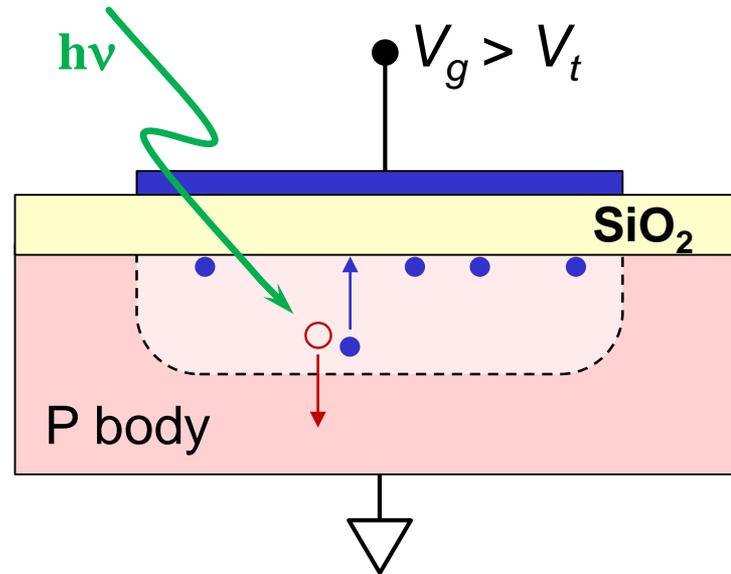
- Assume that  $V_{ox}$ , the voltage across a 2nm thin oxide is 1V. The N<sup>+</sup> poly-gate doping is  $N_{poly} = 8 \times 10^{19} \text{ cm}^{-3}$  and substrate  $N_a = 10^{17} \text{ cm}^{-3}$ . Assuming that channel is inverted, estimate:
  - a)  $W_{dpoly}$
  - b)  $\phi_{poly}$
  - c)  $V_g$

# CCD Imager

- In CMOS imager, photodiode is used as photo-detector and CMOS circuitry is used to convert charge to voltage and amplify and transmit that voltage to output circuits
- In CCD imager, MOS capacitor is used both as a photo-detector and a charge transfer device to move photo-charge from pixel to output circuits
- Suppose a voltage  $V_g > V_t$  is suddenly applied to gate of a MOS capacitor
- Thermal generation is slow – for a period of time there are no inversion electrons.
  - bands bend beyond  $2\phi_B$
  - depletion region extends beyond  $W_{dmax}$
- Known as **deep depletion**



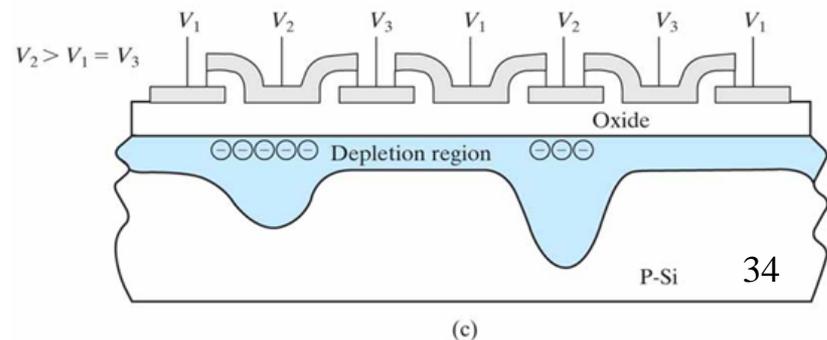
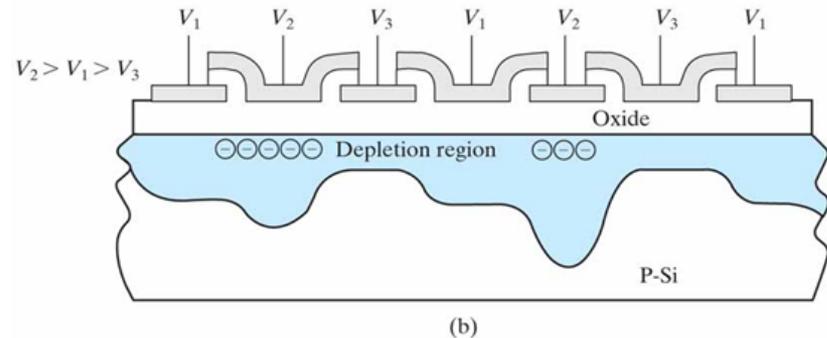
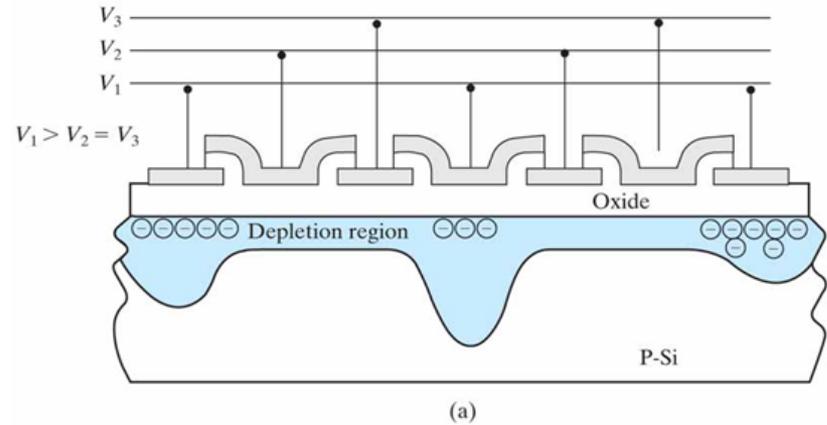
# CCD Photodetector



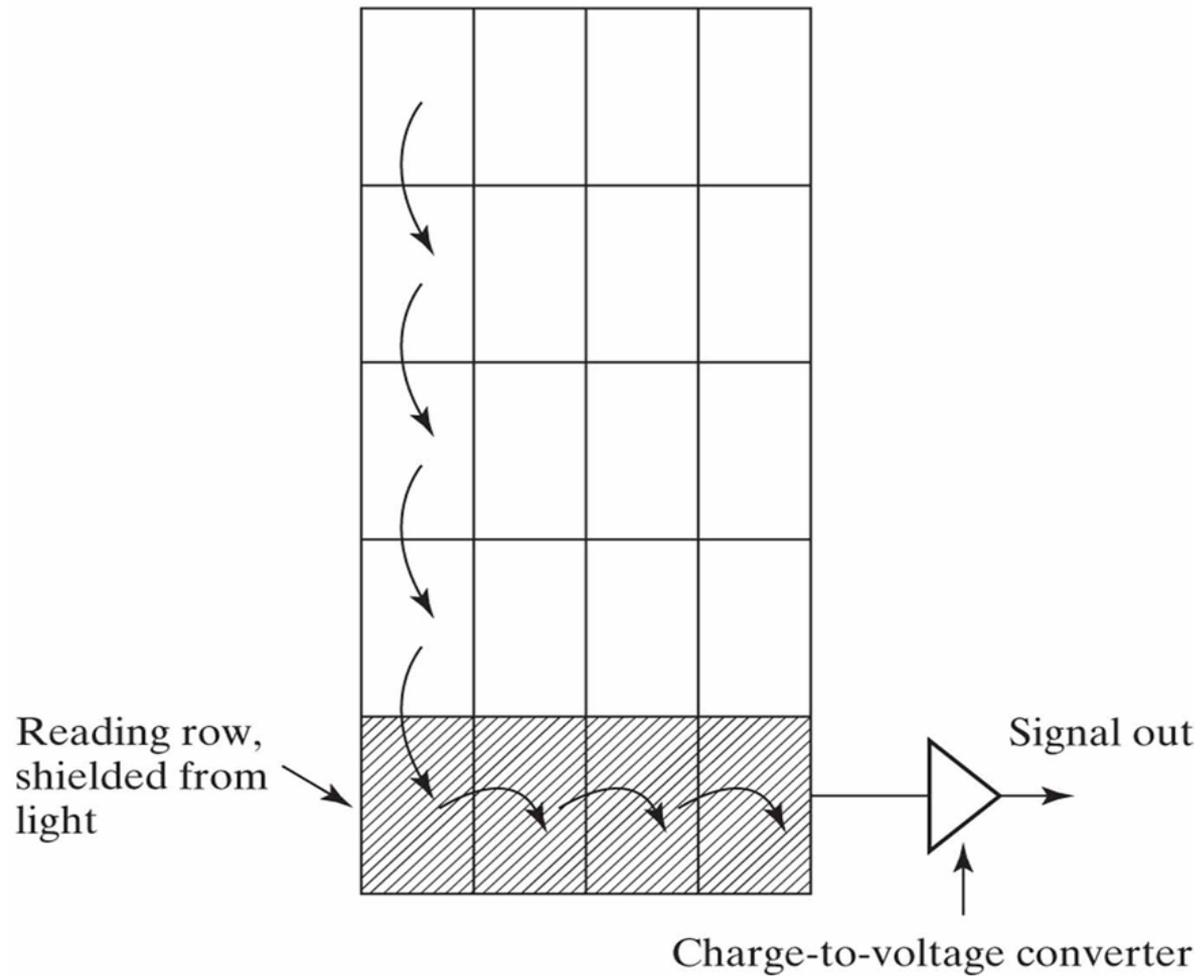
- If light shines on MOS capacitor in deep depletion, photons pass through thin poly gate and generate electron-hole pairs in depletion region
  - Photo-generated holes drift into substrate and are removed through substrate contact
  - Photo-generated electrons drift towards gate and are collected at oxide surface
- Number of electrons collected proportional to light intensity 33

# CCD Charge Transport

- Once electrons are collected under a MOS gate, they can be passed along a row of adjacent gates with suitably timed multiphase clocks
- Every third gate functions as a photo-detector
- At end of exposure time, charges are passed along row toward output circuits
- Overlapping poly gates ensure high charge transfer efficiency



# 2-D CCD Imager



- 2-D array of charge packets are read row by row